

Amendments to the Abstract:

Please rewrite the Abstract as shown below:

ABSTRACT

~~There is disclosed a~~ A piezoelectric/electrostrictive film type actuator (11)
~~which comprises~~ is provided including a ceramic substrate (44), and a
piezoelectric/electrostrictive device (78) disposed on the ceramic substrate (44) and
~~being provided~~ that is provided with a plurality of piezoelectric/electrostrictive film
~~(79) films~~ and electrode film (73, 75, 77); ~~the~~ films. The device ~~being~~ is driven by
displacement of the piezoelectric/electrostrictive device (78); ~~and the~~. The
piezoelectric/electrostrictive device (78) ~~wherein~~ includes a plurality of layers of
piezoelectric/electrostrictive films, and the piezoelectric/electrostrictive film (79) films
and electrode film (73, 75, 77) films are alternately laminated ~~to form the~~ such that an
electrode ~~from a film forms an~~ uppermost layer and a lowermost layer ~~possesses a~~
~~plurality of layers of the~~ piezoelectric/electrostrictive ~~device~~ films (79). The
piezoelectric/electrostrictive film type actuator is superior in that it can easily highly
be integrated without including a structure laminated using an adhesive, and attain a
larger displacement with the same driving voltage, a fast response speed and a large
generation force.